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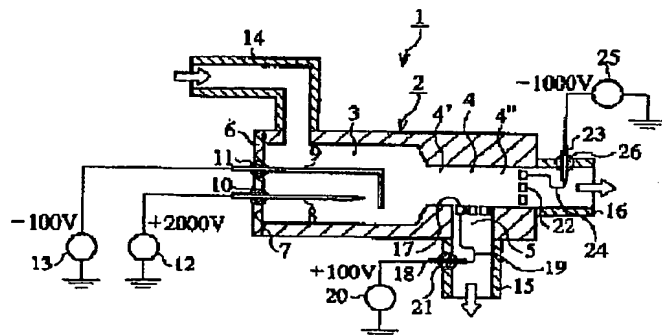
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TITLE : METHOD AND APPARATUS FOR GAS PURIFICATION



ABSTRACT : PROBLEM TO BE SOLVED: To provide an ultra-pure gas from which impurities are fully removed.

SOLUTION: Nitrogen gas which flows into a gas leading pipe 14 is divided to a first flow out path comprising a discharge hole 5 and the inside of a discharge pipe 15 and a second flow out path comprising a part 4'' of a discharge hole 4 and a discharge pipe 16 and flows out of respective discharge pipes 15, 16. Nitrogen gas is primarily ionized by corona discharge generated between a discharge probe and an opposed electrode 9 in a discharge chamber 3, successively secondarily ionized, and consequently impurities, such as oxygen, in the nitrogen gas are ionized to be positive ions. The impurities, e.g. oxygen, ionized to bear positive charge receive repulsion from a positive electrode 17 and at the same time receive attraction from a negative electrode 22 and mainly flow out of the discharge pipe 16 and scarcely flow out of the discharge pipe 15. Consequently, nitrogen gas with ultrahigh purity from which impurities are removed is obtained through the discharge pipe 15.

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